AMENDMENTS TO THE SPECIFICATION:

Please replace the title of the invention, stated on line 1 of page 1, with the following:

MICROMECHANICAL DEVICE FABRICATION

Please replace the paragraph beginning on line 3 of page 1 with the following rewritten paragraph:

The following patents and/or commonly assigned patent applications are hereby incorporated herein by reference:

Patent No.	Filing Date	Issue Date	Title
5,061,049	Sept. 13, 1990	Oct. 29, 1991	Spatial Light Modulator and Method
5,583,688	Dec. 21, 1993	Dec. 10, 1996	Multi-Level Digital Micromirror Device
-	June 21, 2000 June 21, 2001		Re-coating MEMS devices Using Dissolved
	7 3 3 7 7 7 7 7 7 7 7 7 7 7 7 7 7 7 7 7		Resins
TI-29135 10/038,791	Herewith Dec. 31, 2001		Micromechanical Device Recoat Methods

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